

**Amendments to the Specification:**

Please amend the title as follows:

PRESSURE SENSOR DEVICE INCLUDING A DIAPHRAGM AND A  
STOPPER MEMBER HAVING A CURVED SURFACE FACING THE  
DIAPHRAGM

Please amend the paragraph at page 13, line 29 to page 14,  
line 15 as follows:

The base body 21 is made up of a silicon substrate, the principal surface of which is, for example, a (100) surface. As shown in Fig. 8, a central portion thereof serves as a circular main diaphragm portion 21a that detects differential pressure  $\Delta p$  applied to between both sides thereof with high sensitivity. The rim portion of the main diaphragm portion 21a of the base body 21 is used as a circular auxiliary diaphragm portion ~~22b~~ 21b for detecting ~~after-mentioned~~ static pressure (mentioned below). Specifically, four strain resistance gauges R11, R12, R13 and R14 for differential pressure detection, which extend in a <110> direction, are formed at intervals of 90 degrees near the rim portion of the main diaphragm portion 21a. In

the auxiliary diaphragm portion 21a, four strain resistance gauges R21, R22, R23 and R24 for static pressure detection, which extend in the <110> direction, are arranged at intervals of 90 degrees. Moreover, in a rim position deviated from the diaphragm portions 21a and 21b of the base body 21, there is formed a resistor Rt for temperature detection, which extends in a <100> direction.

Please amend the paragraph at page 14, lines 16-21 as follows:

In the auxiliary diaphragm portion ~~22b~~ 21b, there is formed a through-hole ~~22c~~ 21c piercing through the front and rear faces of the base body 21. The through-hole ~~22c~~ 21c is designed to lead a pressure-transmitting medium such as silicone oil to both sides of the auxiliary diaphragm portion ~~22b~~ 21b as described below.